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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT APPLICATION of

Shuichi Noda

Group Art Unit: 1765

Serial No.: 10/084,192 ✓

Examiner: Deo, Euy Vu Nguyen

Filed: February 28, 2002

Confirmation No. 4931

METHOD FOR ETCHING AN
ANTIREFLECTIVE COATING AND FOR
FABRICATING A SEMICONDUCTOR
DEVICE

**REQUEST FOR ACKNOWLEDGMENT OF RECEIPT OF
CERTIFIED COPY OF PRIORITY DOCUMENT**

Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

On February 28, 2002, a Claim of Priority was filed in the subject application, copy attached. As of the present date, however, acknowledgment of receipt of the priority document has not been made.

Please check the file of the above-identified application and confirm that the priority document has been received.

Respectfully submitted,

VOLENTINE FRANCOS, PLLC

Adam C. Volentine
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Reston, Virginia 20191
Telephone No.: (703) 715-0870
Facsimile No.: (703) 715-0877

Dated: May 19, 2004

COPY



REQUEST FOR EARLY NOTIFICATION OF SERIAL NUMBER

ATTY DOCKET #: OKI.310

DUE DATE: August 10, 2002

APPLICANT: Shuichi NODA

SERIAL NO.: (NEW)

FEB 28 2002

FILING DATE: February 28, 2002

TITLE: METHOD FOR ETCHING AN ANTIREFLECTIVE COATING AND FOR FABRICATING A SEMICONDUCTOR DEVICE

RECEIPT OF THE FOLLOWING PAPERS IS ACKNOWLEDGED:

New U.S. Patent Application including: Utility Patent Application Transmittal; Recordation Form Cover Sheet including Assignment (2 pages); specification, claims and abstract (21 pages); Declaration and Power of Attorney (3 pages); 5 sheets of drawings for Figures 1-6e; Claim of Priority including 1 priority document; Transmittal of Information Disclosure Statement, PTO-1449 Form and 1 reference; and \$780 filing fee.

DATE: February 28, 2002

ATTY: ACV

[Check No. 9523]



COPY

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of :

Shuichi NODA :

Serial No.: [NEW] :

Attn: Applications Branch

Filed: February 28, 2002 :

Attorney Docket No.: OKI.310

For: METHOD FOR ETCHING AN ANTIREFLECTIVE COATING AND FOR
FABRICATING A SEMICONDUCTOR DEVICE

CLAIM OF PRIORITY

Honorable Assistant Commissioner for Patents and Trademarks,
Washington, D.C. 20231

Sir:

Applicant, in the above-identified application, hereby claims the priority date
under the International Convention of the following Japanese application:

Appln. No. 2001-243275 filed August 10, 2001

as acknowledged in the Declaration of the subject application.

A certified copy of said application is being submitted herewith.

Respectfully submitted,

VOLENTINE FRANCOS, PLLC


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Date: February 28, 2002

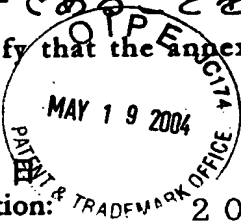


本 国 特 許 庁
JAPAN PATENT OFFICE

COPY

別紙添付の書類に記載されている事項は下記の出願書類に記載されて
いる事項と同一であることを証明する。

This is to certify that the annexed is a true copy of the following application as filed
with this Office



出 願 年 月 日
Date of Application: 2001年 8月10日

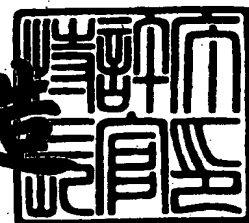
出 願 番 号
Application Number: 特願2001-243275

出 願 人
Applicant(s): 沖電気工業株式会社

2001年10月26日

特 許 庁 長 官
Commissioner,
Japan Patent Office

及 川 耕 造



出証番号 出証特2001-3094371